



Nanotechnology: Techniques and Instrumentations for Modeling and Characterization Data, Volume II

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Deadline for manuscript
submissions:
closed (31 January 2022)

Message from the Guest Editor

Dear Colleagues,

We take great pleasure to have you informed that this Special Issue is open for submission. We cordially invite you to contribute to this issue. Detailed information can be found at:

https://appls-ci/special_issues/Nanotechnology

The aim of this issue is to offer an opportunity to global in-the-field scholars to share **novel approaches, techniques, and instrumentations for the modeling and characterization of nanomaterials at the nanoscale.**

Specifically, topics of interest for this Special Issue include (but are not limited to):

- State-of-the-art measurement techniques and instruments at the micro- to nanoscale level;
- Methodologies for the quantitative characterization (AFM, STM, SEM, TEM, mass spectrometry, etc.);
- Standards for nanometer-scale characterization;
- Precision instrumentation design and theory;
- Others...

If you wish to check the fit of your manuscript for this Issue prior to submission, you are welcome to send a tentative title and abstract to the editorial office (Ms. Maura Pei: **maura.pei @mdpi.com**) and you will receive feedback shortly.





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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